

Electronic Supplementary Information

Low temperature self-reducible copper hydroxide amino-alcohol complex catalyzed by formic acid for conductive copper films

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Fig. S5 Relative resistance (R/R_0) of sintered Cu films changes with durations in oven under different aging temperatures of (a) 50 °C, (b) 100 °C respectively.

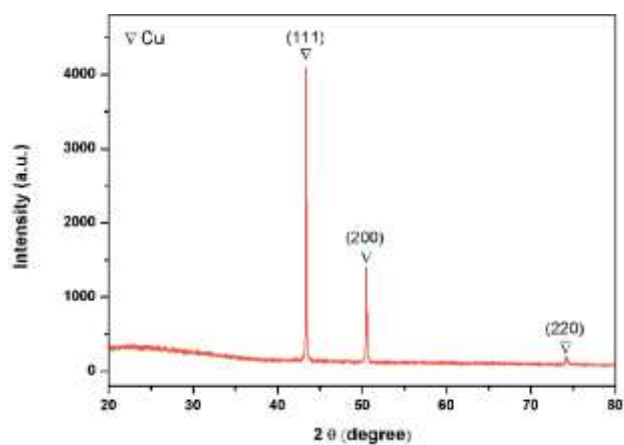


Fig. S1 XRD patterns of $\text{Cu}(\text{HCOO})_2\text{-DMAPD}$ (1:2) sintered at 200 °C for 30 min under a nitrogen atmosphere.

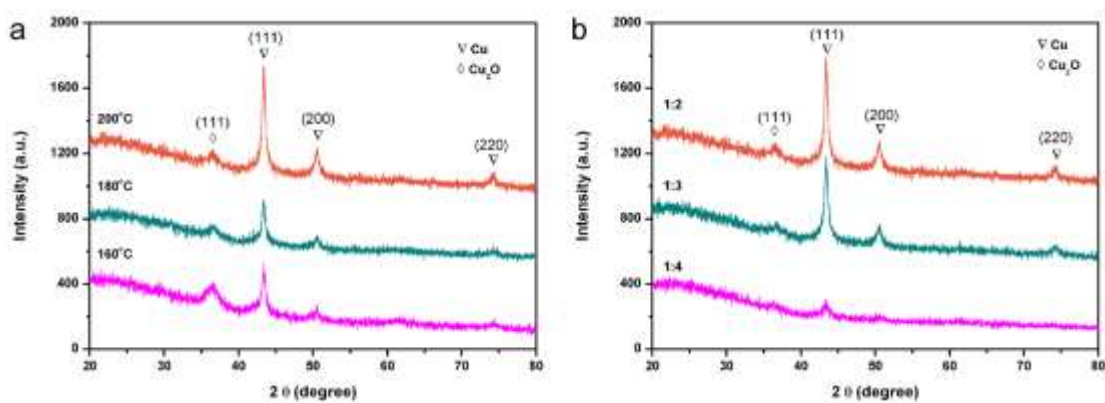


Fig. S2 XRD patterns of (a) $\text{Cu}(\text{OH})_2\text{-DMAPD}$ complex at a molar ratio of 1:2 sintered at 160 °C, 180 °C and 200 °C, (b) $\text{Cu}(\text{OH})_2\text{-DMAPD}$ complex at different molar ratio of 1:2, 1:3 and 1:4 sintered at 200 °C for 30 min under a nitrogen atmosphere.

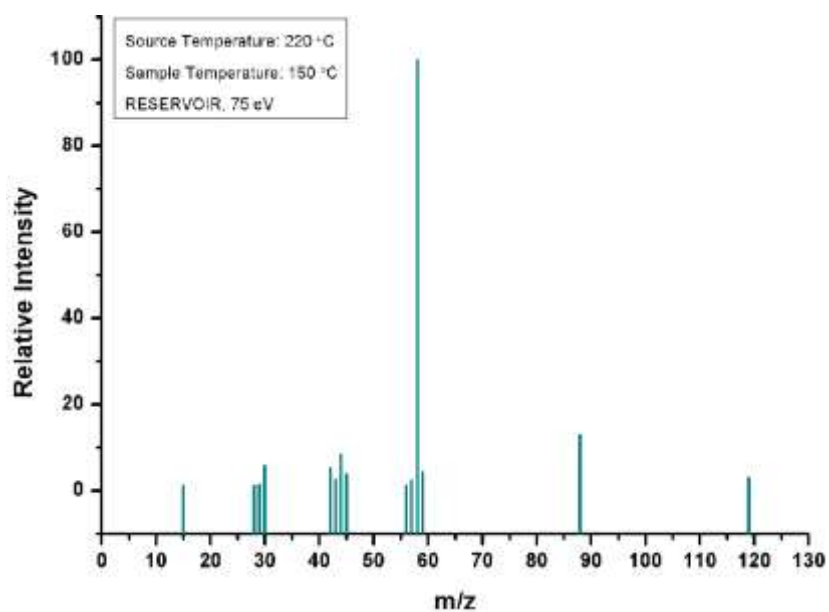


Fig. S3 GC-MS of DMAPD.¹

¹ MS-IW-0916 SDBS NO. 23771 [EB/OL],

http://sdb.db.aist.go.jp/sdb/cgi-bin/direct_frame_top.cgi, 1999-03-31.

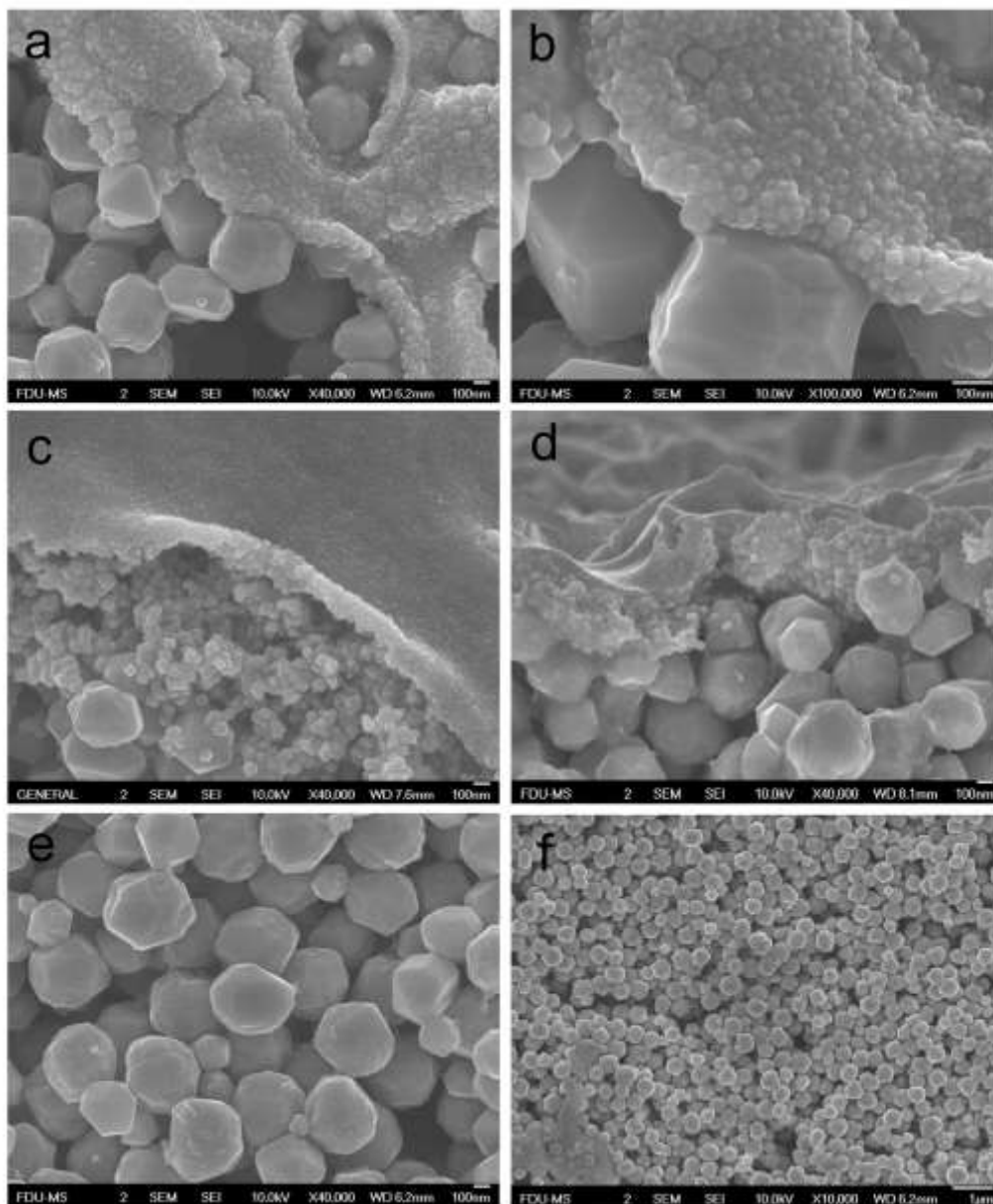


Fig. S4 SEM images of $\text{Cu}(\text{OH})_2\text{-DMAPD-HCOOH}$ (1:2:0.3) sintered at (a-b) 160 °C, and (c) 200 °C (top-view), (d) 200 °C (cross-section); and (e-f) $\text{Cu}(\text{OH})_2\text{-DMAPD-HCOOH}$ (1:2:0.5) sintered at 200 °C under a nitrogen atmosphere.

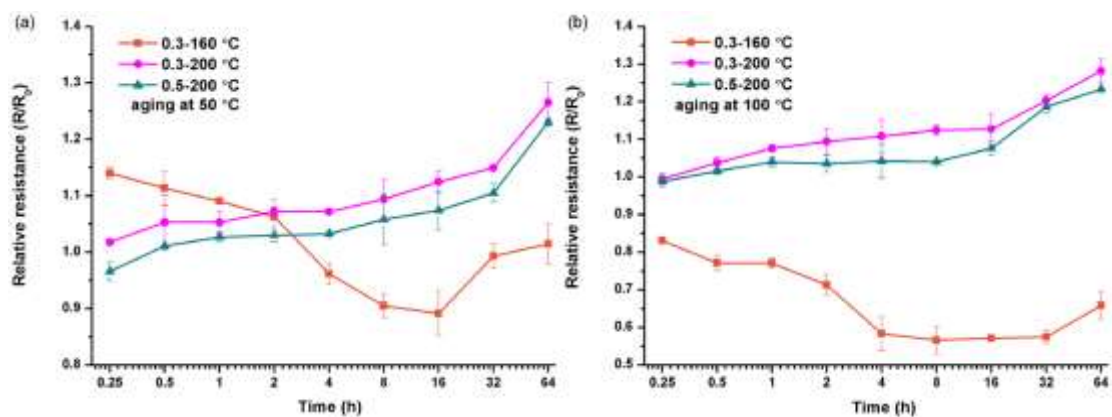


Fig. S5 Relative resistance (R/R_0) of sintered Cu films changes with the aging time at different temperatures (a) 50 °C, (b) 100 °C.

The sample denotations in the figures are as follows.

0.3-160 °C: $\text{Cu}(\text{OH})_2\text{-DMAPD-HCOOH}$ (1:2:0.3) complex sintered at 160 °C;

0.3-200 °C: $\text{Cu}(\text{OH})_2\text{-DMAPD-HCOOH}$ (1:2:0.3) complex sintered at 200 °C;

0.5-200 °C: $\text{Cu}(\text{OH})_2\text{-DMAPD-HCOOH}$ (1:2:0.5) complex sintered at 200 °C.